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Wibool Piyawattanametha
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Contents

- vii *Conference Committee*
- ix *Introduction*
- xi *Toy Story: what I have learned from playing with toys about the physics of living cells (Plenary Paper) [7929-203]*
R. H. Austin, Princeton Univ. (United States)

MOEMS-MEMS PLENARY SESSION

- 7930 03 **Lateral spread of MEMS WDM technologies (Plenary Paper) [7930-202]**
H. Toshiyoshi, The Univ. of Tokyo (Japan)

MEMS-BASED ENDOMICROSCOPY: JOINT SESSION WITH CONFERENCE 7893

- 7930 04 **MEMS-based laser scanning microscope for endoscopic use [7930-01]**
U. Schelinski, J. Knobbe, H. Dallmann, H. Grüger, M. Förster, M. Scholles, M. Schwarzenberg, Fraunhofer Institute for Photonic Microsystems (Germany); R. Rieske, Dresden Univ. of Technology (Germany)
- 7930 05 **An improved focus control mirror using SU-8 wafer bonding process [7930-02]**
M. J. Moghimi, Montana State Univ. (United States); B. J. Lutzenberger, Bridger Photonics, Inc. (United States); K. Oliver, S. Gates, X. Xue, Montana State Univ. (United States); B. Kaylor, Bridger Photonics, Inc. (United States); D. L. Dickensheets, Montana State Univ. (United States)
- 7930 06 **SU-8 focus control mirrors released by XeF₂ dry etch [7930-03]**
S. J. Lukes, D. L. Dickensheets, Montana State Univ. (United States)

DISPLAY AND IMAGING I

- 7930 08 **Electrowetting-based liquid lenses for endoscopy (Invited Paper) [7930-05]**
S. Kuiper, Philips Research Eindhoven (Netherlands)
- 7930 09 **Liquid crystal lens auto-focus extended to optical image stabilization for wafer level camera [7930-06]**
N. Fraval, F. Berier, Evosens (France)
- 7930 0A **Tunable liquid lens with reduced chromatic and spherical aberration [7930-07]**
H. Yu, G. Zhou, F. S. Chau, H. Leung, National Univ. of Singapore (Singapore)
- 7930 0B **A multi-aperture approach to wafer-level camera lenses [7930-08]**
A. Brückner, R. Leifel, P. Dannberg, F. Wippermann, A. Bräuer, Fraunhofer Institute for Applied Optics and Precision Engineering (Germany)

- 7930 0C **Ultra-compact imaging system based on multi-aperture architecture** [7930-09]
J. Meyer, A. Brückner, R. Leitel, P. Dannberg, A. Bräuer, Fraunhofer Institute for Applied Optics and Precision Engineering (Germany); A. Tünnermann, Fraunhofer Institute for Applied Optics and Precision Engineering (Germany) and Friedrich Schiller Univ. of Jena (Germany)
- 7930 0D **Design of an ultra-thin objective lens based on superposition compound eye** [7930-10]
A. Garza-Rivera, F. J. Renero-Carrillo, Instituto Nacional de Astrofísica, Óptica y Electrónica (Mexico)

DISPLAY AND IMAGING II

- 7930 0E **Microbolometers for thermography and night vision markets (Invited Paper)** [7930-11]
E. Mounier, Yole Développement (France)
- 7930 0F **MEMS-based handheld projection systems and a survey of applications** [7930-12]
M. K. Brown, G. Valliath, T. Masood, M. Niesten, D. DeJong, Microvision, Inc. (United States)
- 7930 0G **MEMS scanned laser head-up display** [7930-13]
M. O. Freeman, Microvision, Inc. (United States)
- 7930 0H **Vertical electrostatically 90° turning flaps for reflective MEMS display** [7930-14]
F. Jutzi, W. Noell, N. F. de Rooij, Ecole Polytechnique Fédérale de Lausanne (Switzerland)

MICROSPECTROSCOPY AND OPTICAL FILTER

- 7930 0I **Out-of-plane translatory MEMS actuator with extraordinary large stroke for optical path length modulation** [7930-15]
T. Sandner, T. Grasshoff, H. Schenk, Fraunhofer Institute for Photonic Microsystems (Germany); A. Kenda, Carinthian Tech Research AG (Austria)
- 7930 0J **Characterization of MEMS FTIR spectrometer** [7930-17]
D. Khalil, Y. Sabry, Ain Shams Univ. (Egypt) and Si-Ware Systems (Egypt); H. Omran, M. Medhat, A. Hafez, B. Saadany, Si-Ware Systems (Egypt)
- 7930 0K **Tunable mid-infrared filter based on Fabry-Pérot interferometer with two movable reflectors** [7930-18]
M. Meinig, S. Kurth, Fraunhofer-Institut für Elektronische Nanosysteme (Germany); K. Hiller, Chemnitz Univ. of Technology (Germany); N. Neumann, M. Ebermann, InfraTec GmbH (Germany); E. Gittler, JENOPTIK Optical Systems GmbH (Germany); T. Gessner, Fraunhofer-Institut für Elektronische Nanosysteme (Germany) and Chemnitz Univ. of Technology (Germany)
- 7930 0L **Fabrication and testing of MEMS-based optical filter combined with a HgCdTe detector** [7930-19]
D. A. Kozak, Univ. of California, Santa Cruz (United States) and EPIR Technologies, Inc. (United States); B. Fernandez, Univ. of California, Santa Cruz (United States); M. L. Morley, S. Velicu, EPIR Technologies, Inc. (United States); J. Kubby, Univ. of California, Santa Cruz (United States)

DEVICES FOR SPACE APPLICATIONS: JOINT SESSION WITH CONFERENCE 7928 AND 7931

- 7930 OM **Ultra-low-power multiplexed electronic driver for high resolution deformable mirror systems** [7930-20]
M. N. Horenstein, R. Sumner, P. Miller, Boston Univ. (United States); T. Bifano, J. Stewart, S. Cornelissen, Boston Micromachines Corp. (United States)
- 7930 ON **MEMS-based programmable reflective slit mask for multi-object spectroscopy** [7930-21]
M. Canonica, Ecole Polytechnique Fédérale de Lausanne (Switzerland); F. Zamkotsian, P. Lanzoni, Lab. d'Astrophysique de Marseille (France); W. Noell, N. de Rooij, Ecole Polytechnique Fédérale de Lausanne (Switzerland)
- 7930 OO **Focal plane array spectrometer: miniaturization effort for space optical instruments** [7930-36]
B. Guldemann, S. Kraft, European Space Research and Technology Ctr. (Netherlands)

MOEM COMPONENTS AND SYSTEMS I

- 7930 OP **Shaping light with MOEMS (Invited Paper)** [7930-22]
W. Noell, Ecole Polytechnique Fédérale de Lausanne (Switzerland); S. Weber, Ecole Polytechnique Fédérale de Lausanne (Switzerland) and Univ. de Genève (Switzerland); J. Masson, Ecole Polytechnique Fédérale de Lausanne (Switzerland); J. Extermann, L. Bonacina, Univ. de Genève (Switzerland); A. Bich, SUSS MicroOptics SA (Switzerland); R. Bitterli, H. P. Herzig, Ecole Polytechnique Fédérale de Lausanne (Switzerland); D. Kiselev, Univ. de Genève (Switzerland); T. Scharf, Ecole Polytechnique Fédérale de Lausanne (Switzerland); R. Voelkel, K. J. Weible, SUSS MicroOptics SA (Switzerland); J.-P. Wolf, Univ. de Genève (Switzerland); N. F. de Rooij, Ecole Polytechnique Fédérale de Lausanne (Switzerland)
- 7930 OQ **Large diameter dual-axis MEMS-based mirror for laser beam steering** [7930-23]
S. Ilias, F. Picard, K. Le Foulgoc, J. Osouf, C. Larouche, J.-S. Caron, P. Topart, S. Garcia Blanco, INO (Canada); D. Vincent, J. F. Lepage, B. Gilbert, Defence Research and Development Canada (Canada)
- 7930 OR **MEMS scanning laser projection based on high-Q vacuum packaged 2D-resonators** [7930-24]
U. Hofmann, C. Eisermann, H.-J. Quenzer, J. Janes, C. Schroeder, O. Schwarzelbach, B. Jensen, L. Ratzmann, T. Giese, F. Senger, J. Hagge, M. Weiss, B. Wagner, W. Benecke, Fraunhofer Institute for Silicon Technology (Germany)
- 7930 OS **Optical position feedback and phase control of resonant 1D and 2D MOEMS-scanners** [7930-25]
A. Tortschanoff, A. Frank, Carinthian Tech Research AG (Austria); M. Wildenhain, Fraunhofer Institute for Photonic Microsystems (Germany); H. S. Tetikol, Koç Univ. (Turkey); T. Sandner, H. Schenk, Fraunhofer Institute for Photonic Microsystems (Germany); A. Kenda, Carinthian Tech Research AG (Austria)
- 7930 OT **Integration of near-field probes and photonic crystal nanocavities for precise and low-loss resonance control** [7930-26]
X. Chew, G. Zhou, F. S. Chau, National Univ. of Singapore (Singapore)

MOEM COMPONENTS AND SYSTEMS II

- 7930 0U **MEMSEye for optical 3D position and orientation measurement (Invited Paper)** [7930-27]
V. Milanović, N. Siu, A. Kasturi, M. Radojčić;, Y. Su, Mirrorcle Technologies, Inc. (United States)
- 7930 0V **Integrated piezoresistive position detection for electrostatic driven micro scanning mirrors**
[7930-28]
J. Grahmann, T. Graßhoff, H. Conrad, T. Sandner, H. Schenk, Fraunhofer Institute for Photonic Microsystems (Germany)
- 7930 0W **Microfabricated mirrors for space applications** [7930-29]
D. Bayat, C. Ataman, Ecole Polytechnique Fédérale de Lausanne (Switzerland);
B. Guldemann, European Space Research and Technology Ctr. (Netherlands); S. Lani,
W. Noell, N. de Rooij, Ecole Polytechnique Fédérale de Lausanne (Switzerland)
- 7930 0X **Design and fabrication of a pre-aligned free-space optical interconnection device**
[7930-30]
Z. Miao, G. Shao, W. Wang, Louisiana State Univ. (United States)

MOEM COMPONENTS AND SYSTEMS III

- 7930 0Z **Development of on-CMOS chip micro-photonic and MOEMS systems** [7930-32]
L. W. Snyman, T. Okhai, Tshwane Univ. of Technology (South Africa); T. Bourouina, Groupe
ESIEE (France); W. Noell, Ecole Polytechnique Fédérale de Lausanne (Switzerland)
- 7930 10 **In situ surface topography measurement of MOEMS structures under laser exposure**
[7930-34]
A. Mai, M. Krellmann, S. Sinning, S. Wolschke, U. Dauderstädt, H. Schenk, Fraunhofer Institute
for Photonic Microsystems (Germany); D. Schmeißer, Brandenburgische Technische Univ.
Cottbus (Germany); M. Wagner, Fraunhofer Institute for Photonic Microsystems (Germany)

Author Index

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1 MEMS-Based Endomicroscopy: Joint Session with Conference 7893
Wibool Piyawattanametha, NECTEC (Thailand)

2 Display and Imaging I
Jan Grahmann, Fraunhofer Institute for Photonic Microsystems (Germany)

- 3 Display and Imaging II
Harald Schenk, Fraunhofer Institute for Photonic Microsystem
(Germany)
- 4 Microspectroscopy and Optical Filter
Sora Kim, GE Global Research (United States)
- 5 Devices for Space Applications: Joint Session with Conference 7928
and 7931
Sonia Garcia-Blanco, INO (Canada) and Universiteit Twente
(Netherlands)
Joel A. Kubby, University of California, Santa Cruz (United States)
- 6 MOEM Components and Systems I
Wibool Piyawattanametha, NECTEC (Thailand)
- 7 MOEM Components and Systems II
Thilo Sandner, Fraunhofer Institute for Photonic Microsystems
(Germany)
- 8 MOEM Components and Systems III
Jason C. Heikenfeld, University of Cincinnati (United States)

Introduction

On behalf of the organizing and technical program committees, it is our pleasure to welcome you to the Proceedings from the 10th MOEMS and Miniaturized Systems conference which was part of the MOEMS-MEMS symposium of SPIE Photonics West 2011. Once again, the conference offered an outstanding technical program and many opportunities for stimulating discussions. We hope you were able to join and benefit personally and professionally from the meeting, sharing in the enthusiasm that makes the conference an ongoing success. The sessions provided a highly interactive forum for engineers and scientists from all around the world to present and discuss in detail recent advances in emerging technologies. Additionally, a panel discussion highlighted trends and needs for MEMS based applications. If you were unable to join, this proceedings volume will give you a sound insight into the presentations made, and thus, an overview of novel results and development activities in areas like display and imaging, microspectroscopy, scanning mirrors, micromirror arrays, MEMS for space, microendoscopy, and many others.

We want to thank our program committee for the great work they did in soliciting papers and in particular, proposing invited speakers. Special thanks go to Prof. David Dickensheets and Dr. Sonia Garcia-Blanco for the organization of the special session "MEMS-based endomicroscopy" and "Devices for space applications," respectively. Thanks to the speakers of the panel discussion, as well as to the organizers and moderator. Also, we want to thank all the session chairs for working with the authors and keeping the schedule. This conference is made possible only through the diligence and support of key individuals and supporting SPIE staff. Last but not least, we would like to thank all the authors for the technical contributions that are the heart of this conference, and to all the participants who kept discussions lively.

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Wibool Piyawattanametha

